

INSTITUT FÜR MIKROELEKTRONIK-
UND MECHATRONIK-SYSTEME



PI Physik Instrumente

PIEZO NANO POSITIONING

PLANAR MAGNETIC 6D LEVITATING SYSTEM WITH COMPACT SENSOR

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Why does one need this?

- The main advantage of magnetic levitation is the **absence of the mechanical contact**
- In the result, there is **no friction, no abrasive particles; lubricants are not necessary**
- No friction means also no stick-slip → „nm“
- It is suitable for **vacuum use**



Source: youtube.com/

Our targets ...

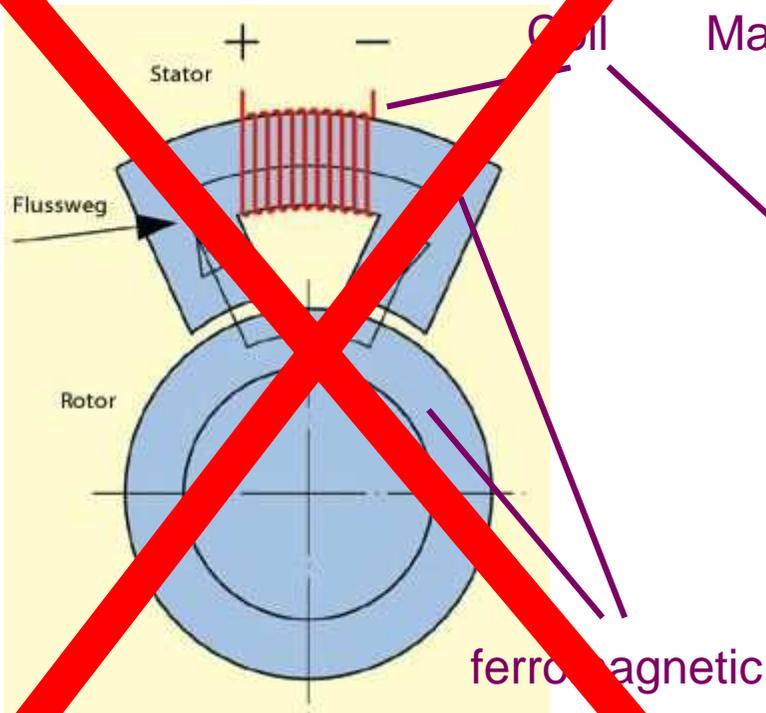
- Get into the 6D magnetic levitation technology
- Realize a traveling range of $x, y, z = 100 \times 100 \times 0,1 \text{ mm}^3$ as a first step
- Minimize the effort → make it “simple”
- Realize a passive stage / no cable to the moved part
- No particle generation
- Integrate a 6D measuring system
- Reach Nanometer resolution
- Keep in mind, that the technology used should be scalable for customized designs



Source: youtube.com/

How can I magnetically levitate something?

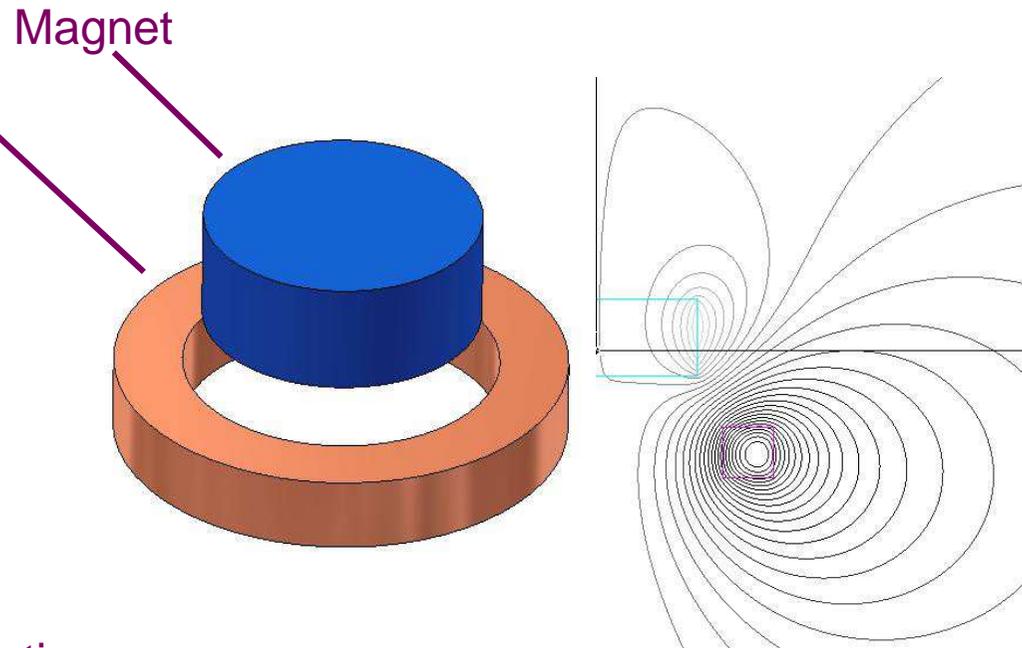
I pull from above



Source: Evolution Online 2012

Reluctance force

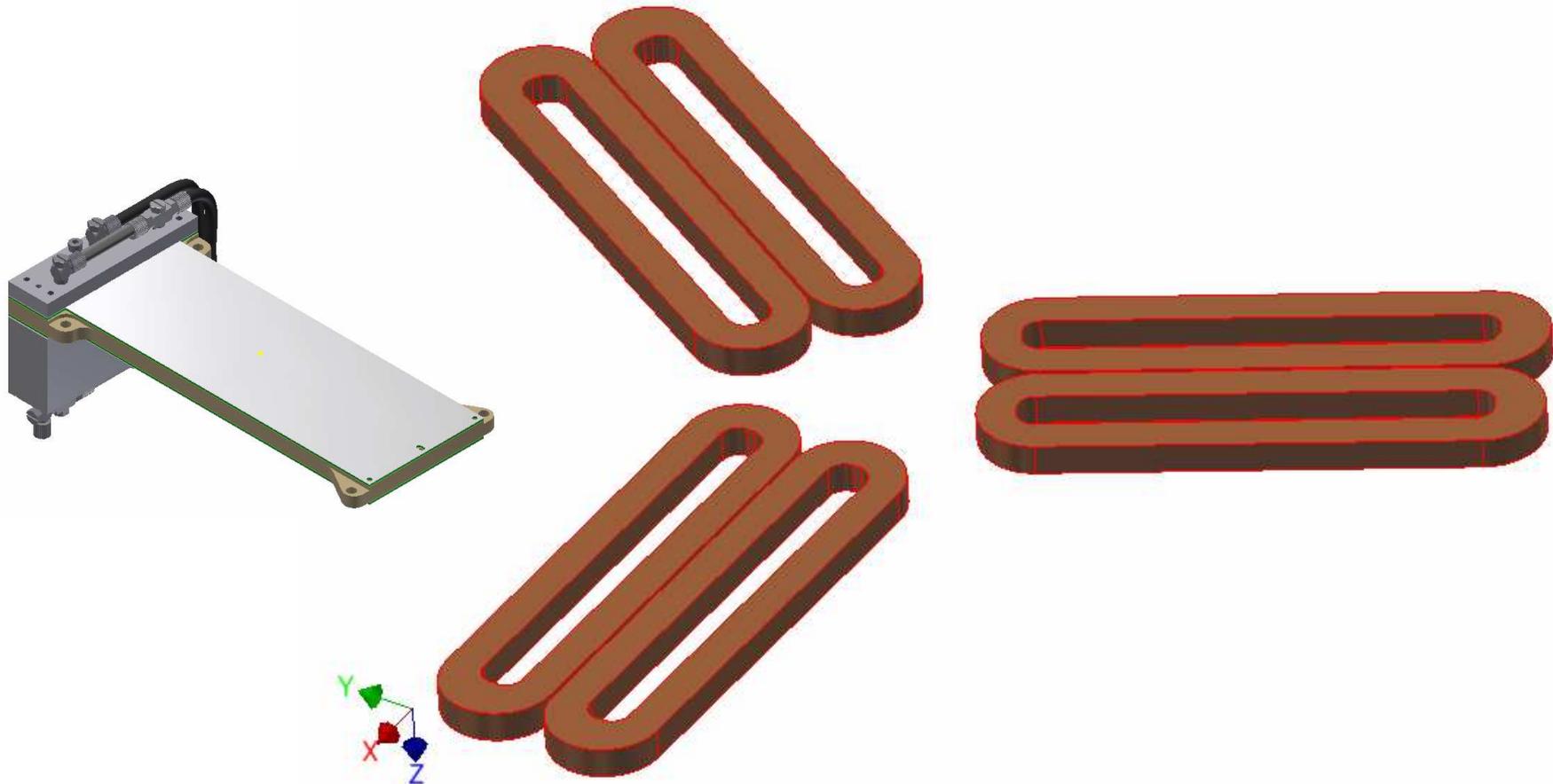
I push from below



Lorentz force

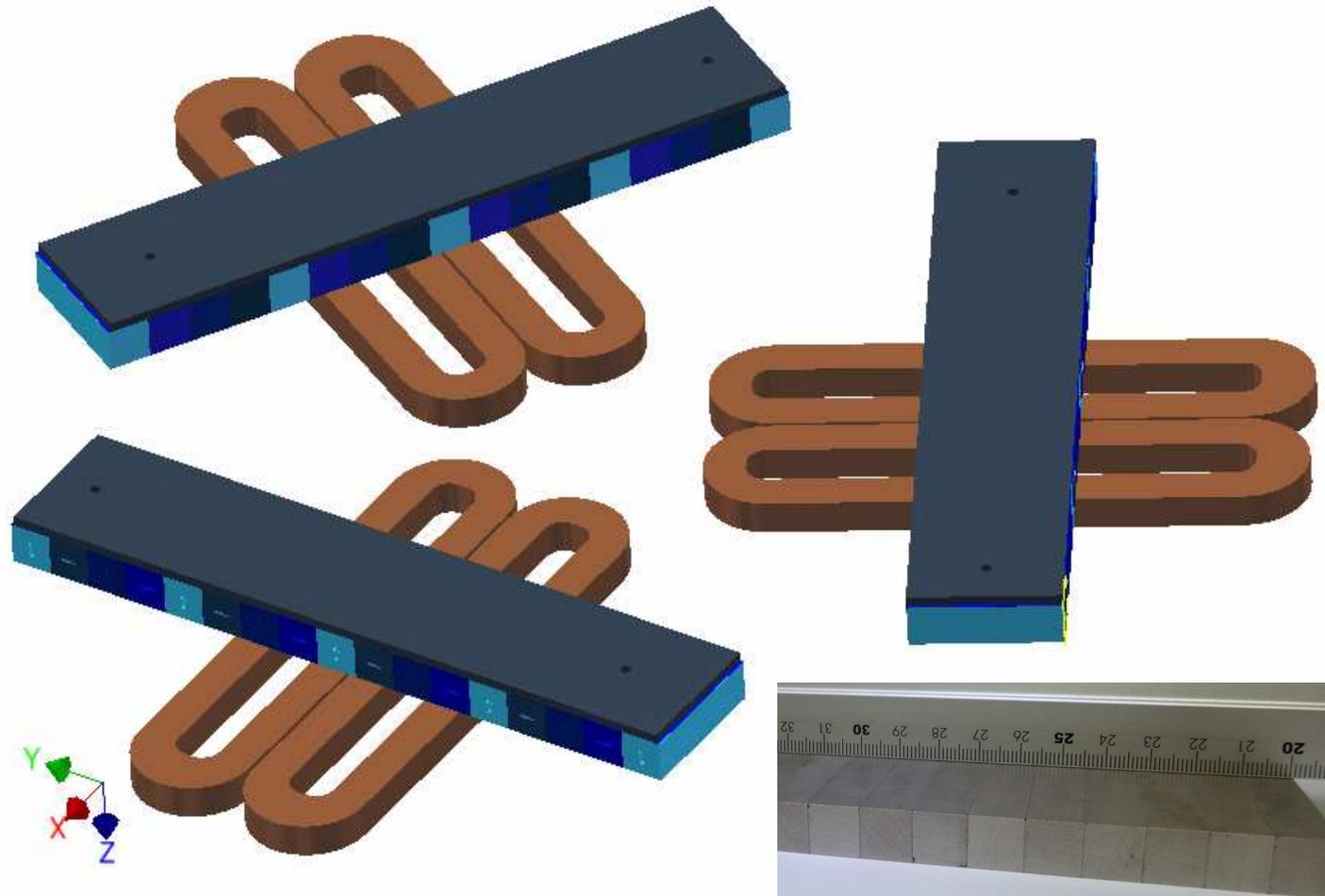
Mag6D - Platform ... The Concept (1)

- 3 coil pairs placed on the stator



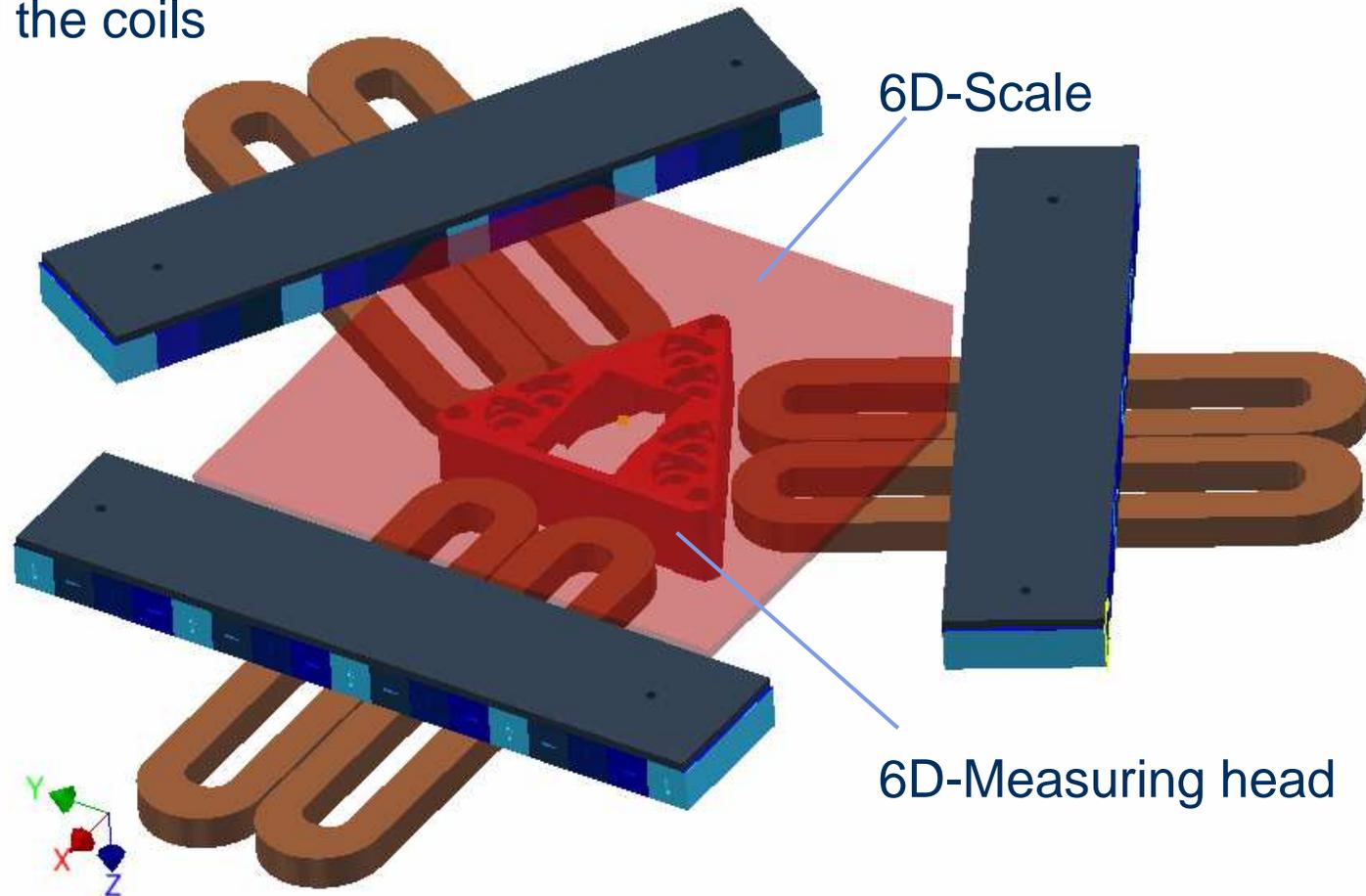
Mag6D - Platform ... The Concept (2)

- 3 Halbach arrays inside the moving stage



Mag6D - Platform ... The Concept (3)

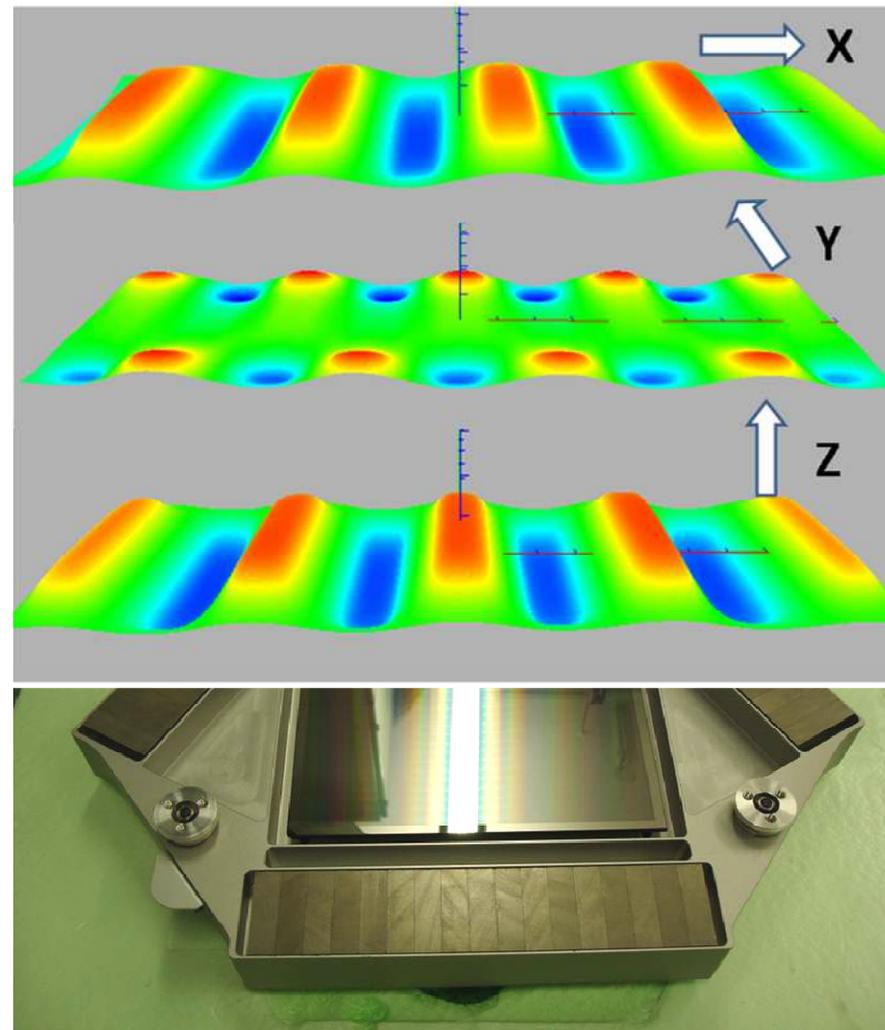
- Free space for a 6D-Measuring system in the center of the magnet array and the coils



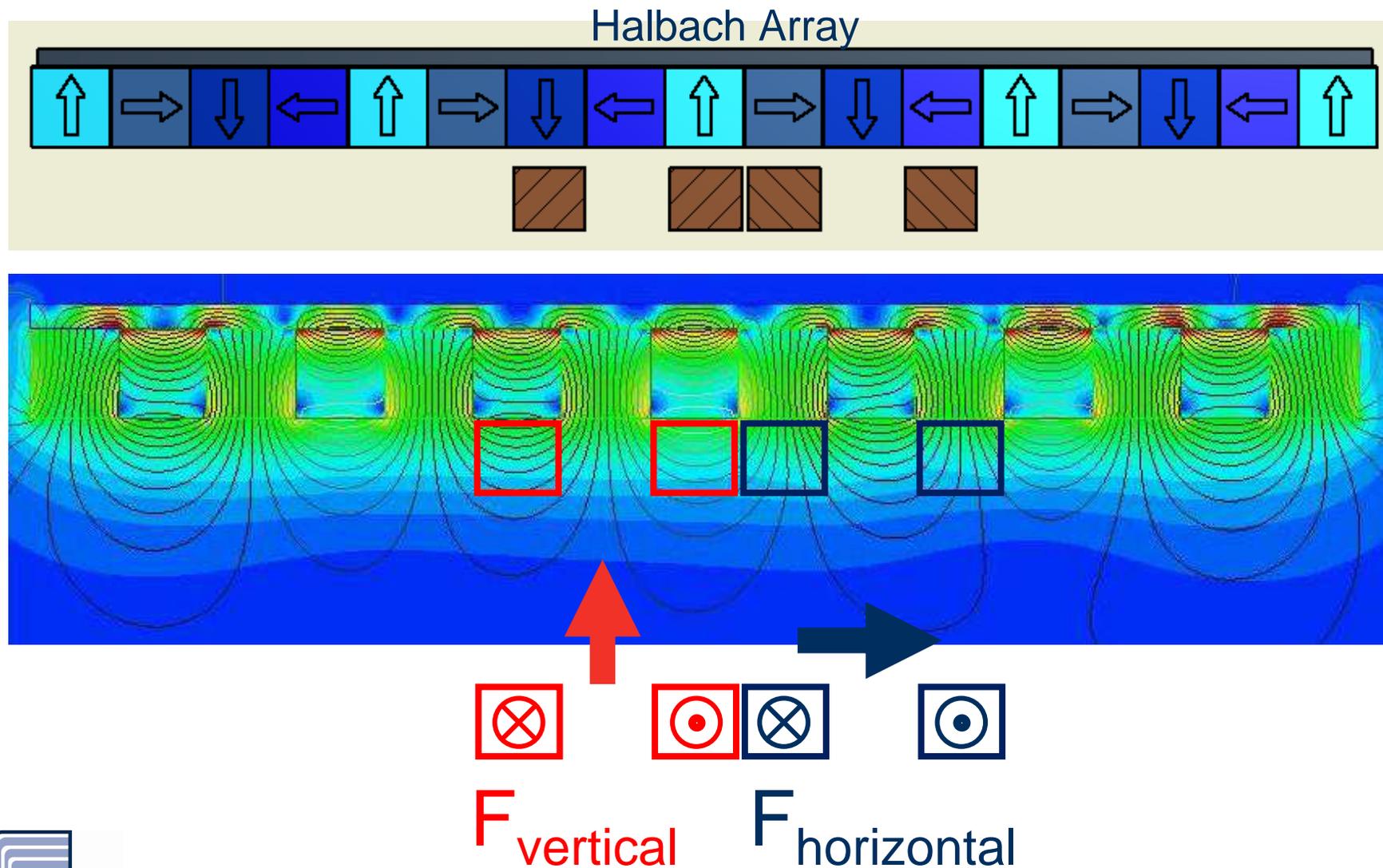
Halbach Array

Advantage:

- Strong magnetic field components on one side of the array
- Strong horizontal field components (for lifting)
- 90 degree phase between the two field components
- Low stray field behind the Halbach array

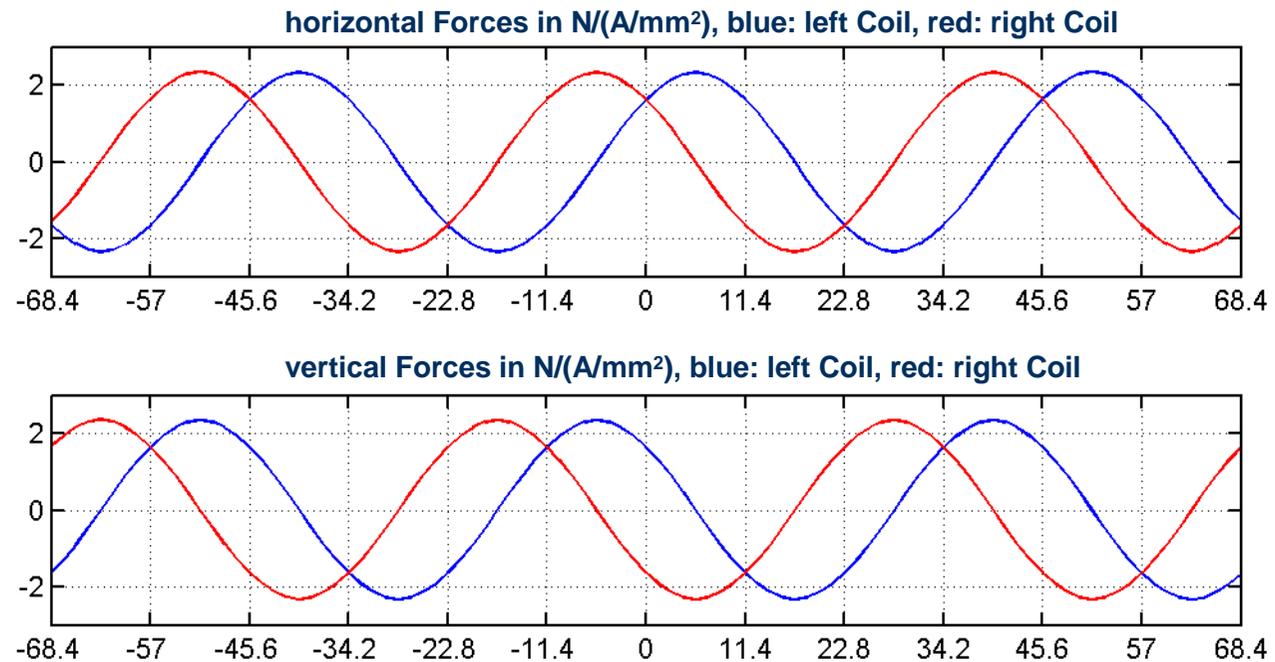
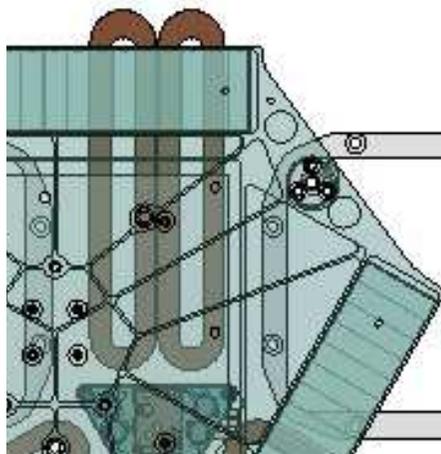


Mag6D - Platform ... Modules → Actor & Guidance (1)

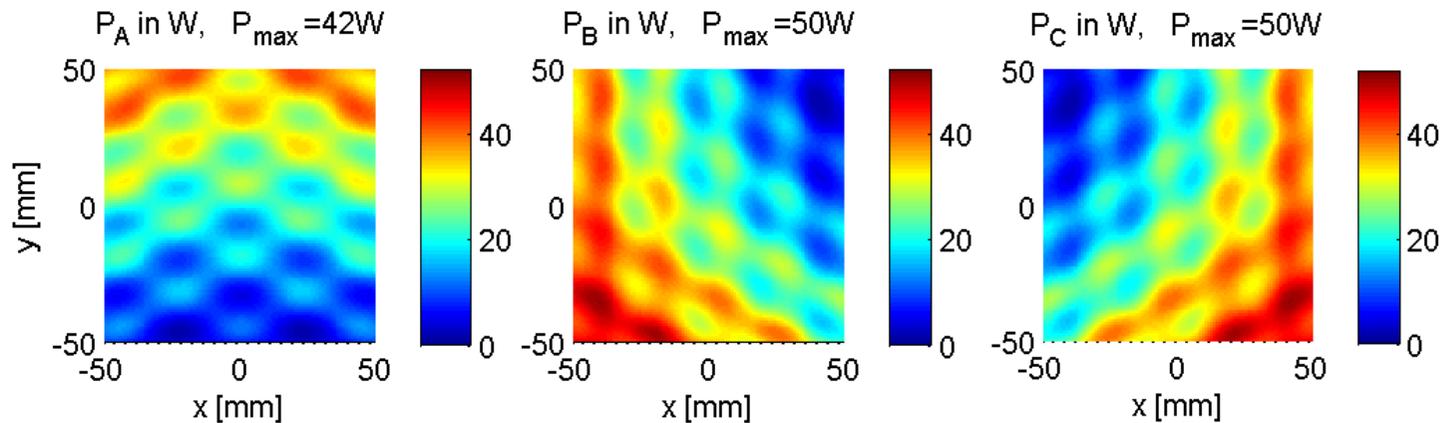


Mag6D - Platform ... Modules → Actor & Guidance (2)

- Position dependent commutation of 3 coil pairs allows the generation of **3 independent lifting forces in vertical direction** and 3 independent driving forces in horizontal direction.
- Resulting in a **6D-Drive system** with only 6 actor coils



Mag6D - Platform ... Modules → Cooling (2)

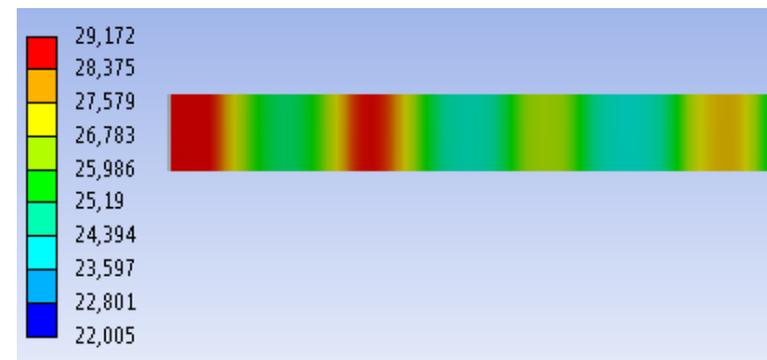


New Design!

Power loss per coil pair vs. slider position

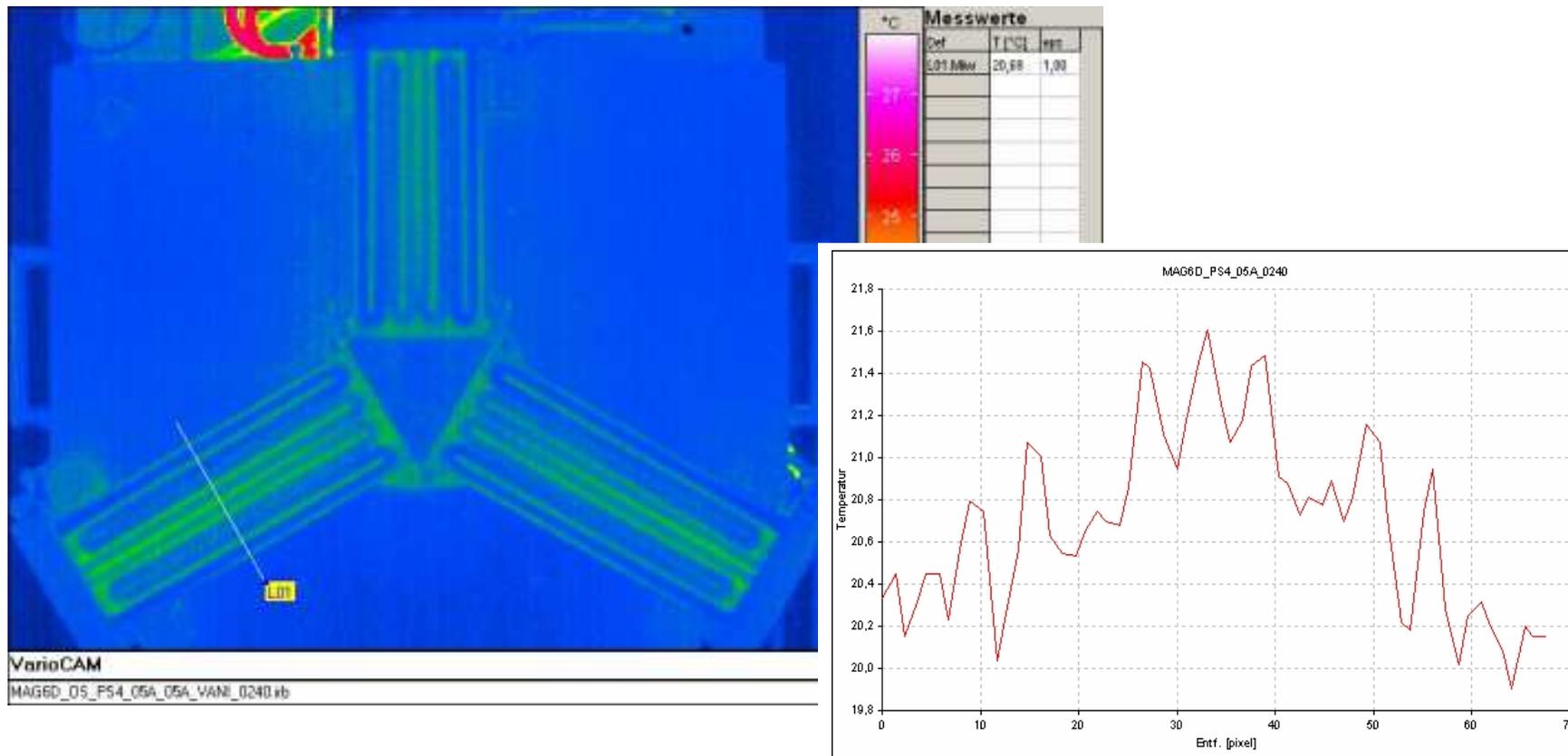


Coil pair with housing



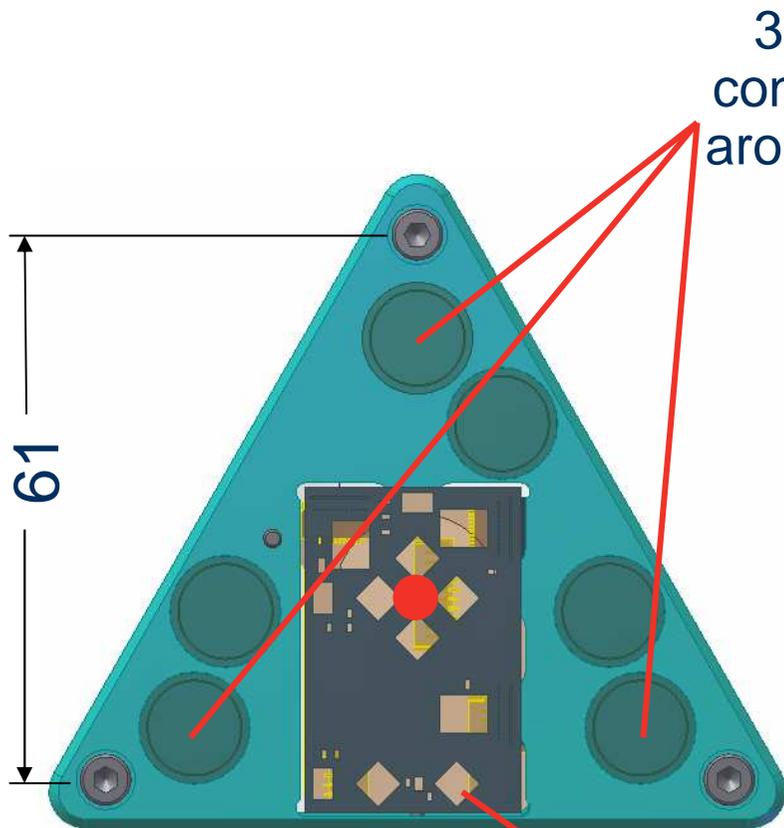
Temperature at top side
(Simulation result worst case)

Mag6D - Platform ... Modules → Cooling (3)

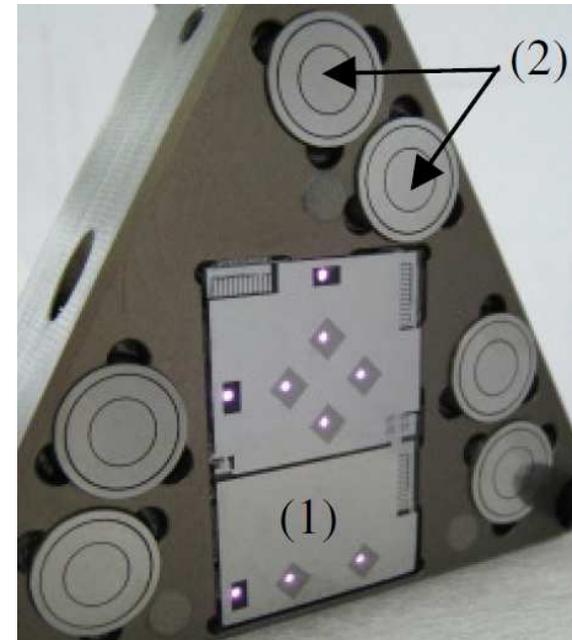


Temperature rise due to a power loss of 40 W per coil after 1 hour

Mag6D - Platform ... Modules → 6D-Measuring system



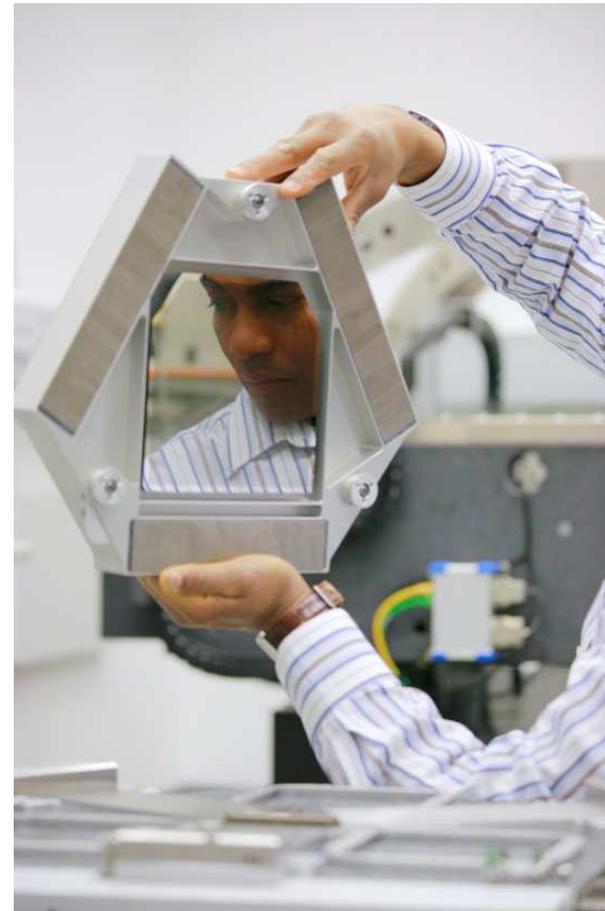
3 z-Sensor pairs (2)
centrically arranged
around the center of the
x-y-r_z-Sensor



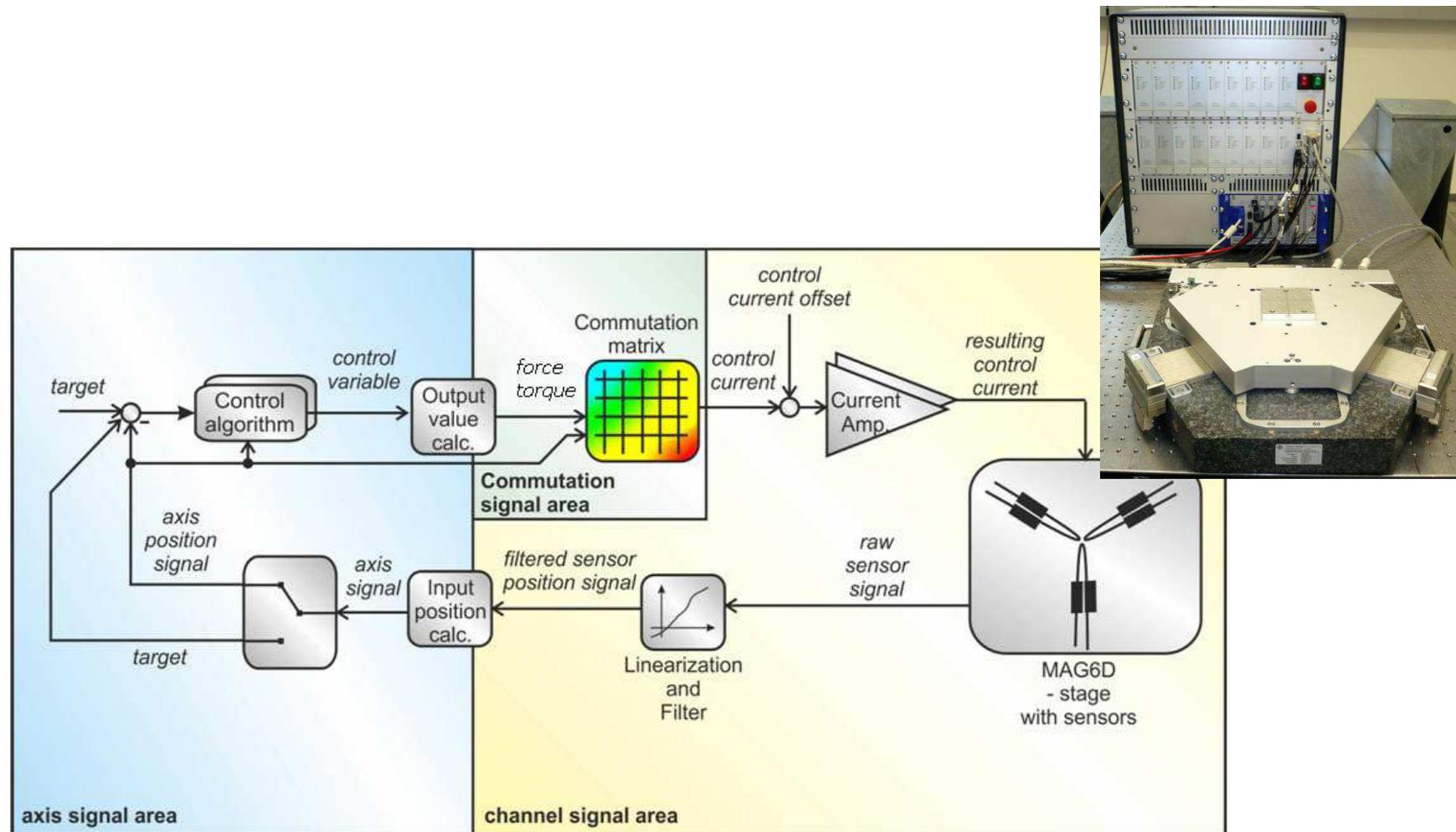
Optical incremental
x-y-r_z-Sensor (1)

Mag6D - Platform ... Parameters

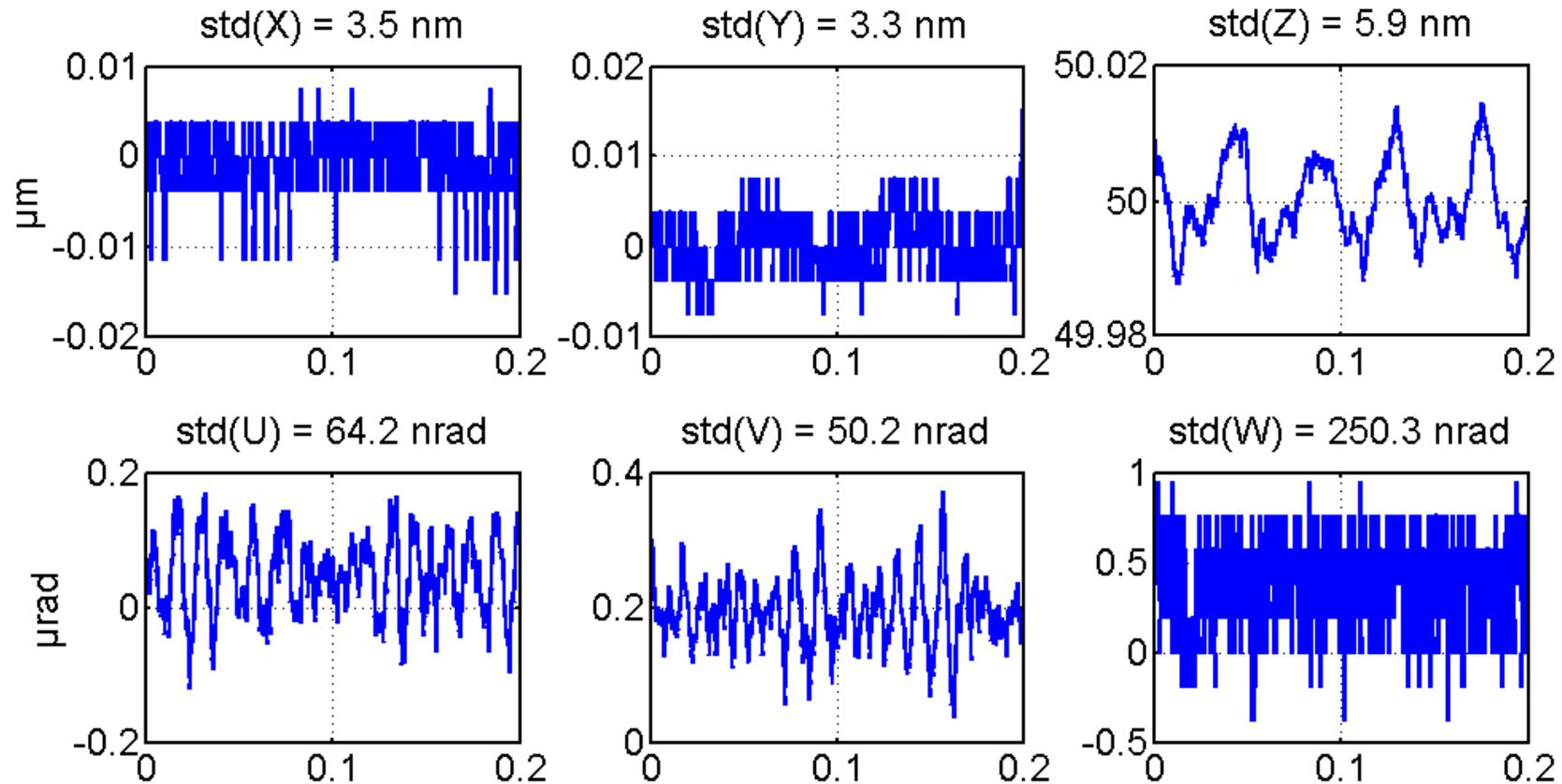
- x,y : 100 x 100 mm²
- z : $\pm 50 \mu\text{m}$
- $r_{x,y}$ $\pm 70 \text{ arcsec}$
- r_z $\pm 0,25^\circ$
- $\text{Res}_{x,y,z}$ 10 nm
- $v_{x,y}$ 100 mm/s
- $a_{x,y}$ 2 m/s²



The electronics - base on PI standard controller E-712

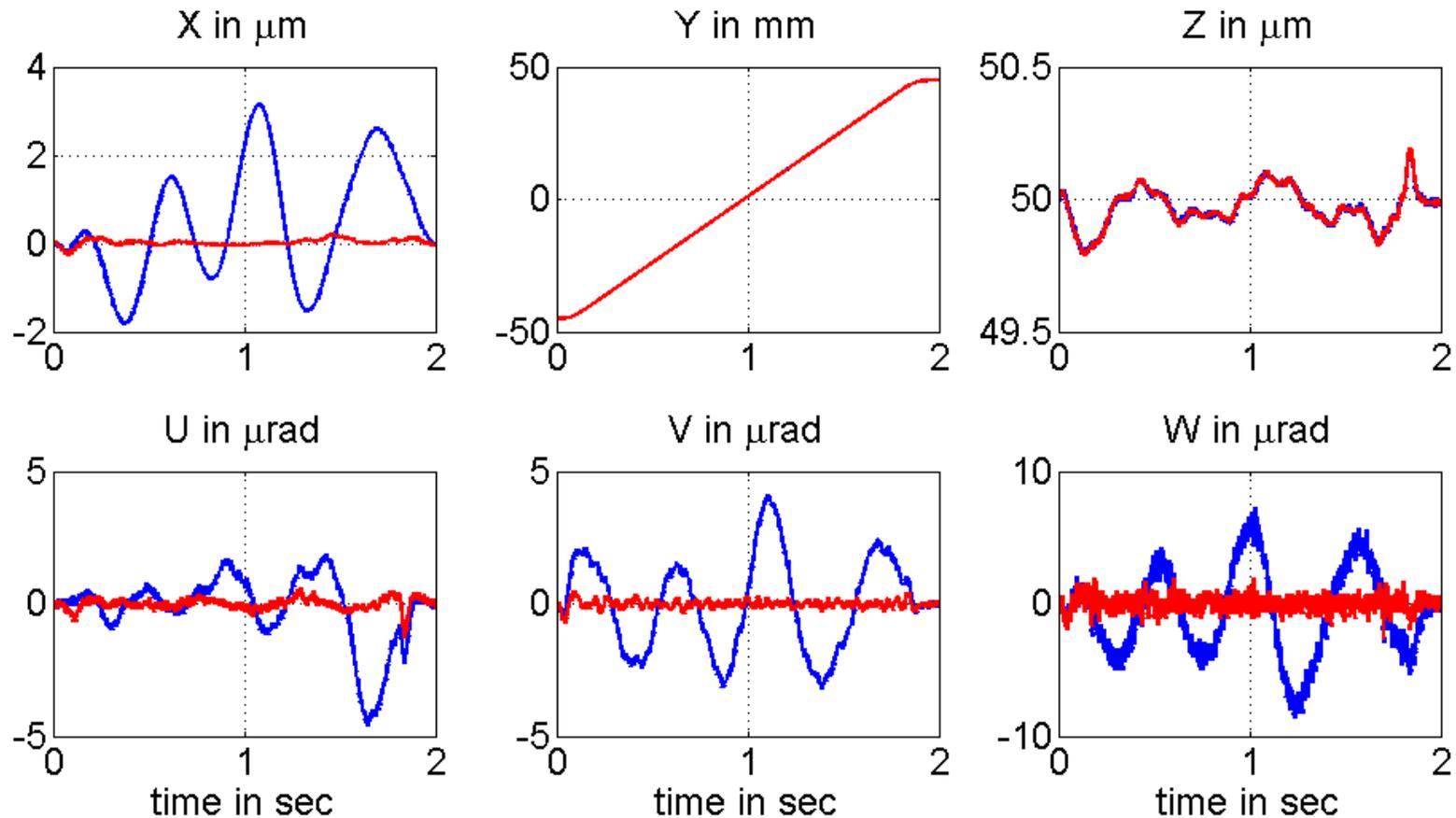


Mag6D - Platform ... Performance (1)



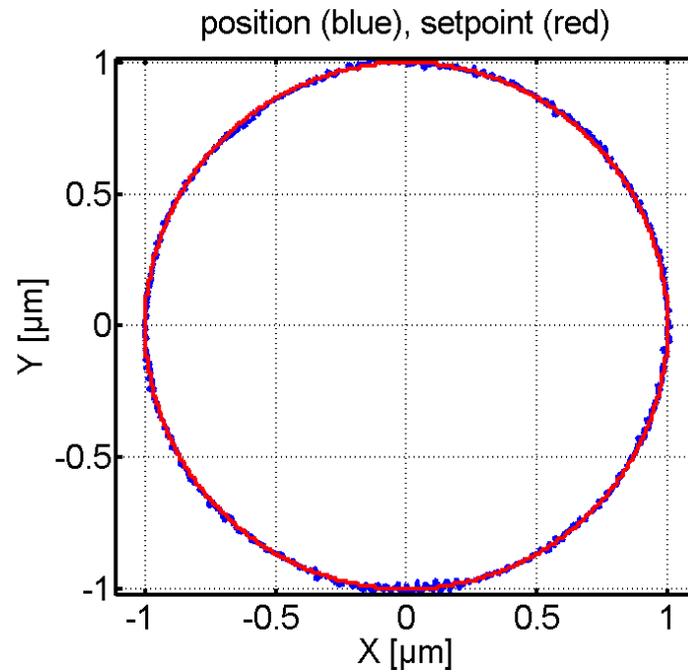
Position stability at position $x=y=0$, $z=50\mu\text{m}$; $u=v=w=0$

Mag6D - Platform ... Performance (2)

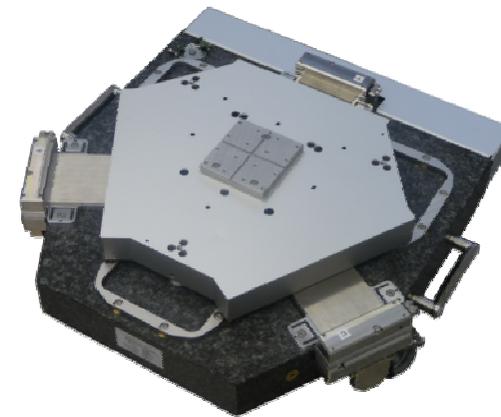


Horizontal movement with 50 mm/s without (blue curves) and with correction matrices (red curves)

Mag6D - Platform ... Performance (3)

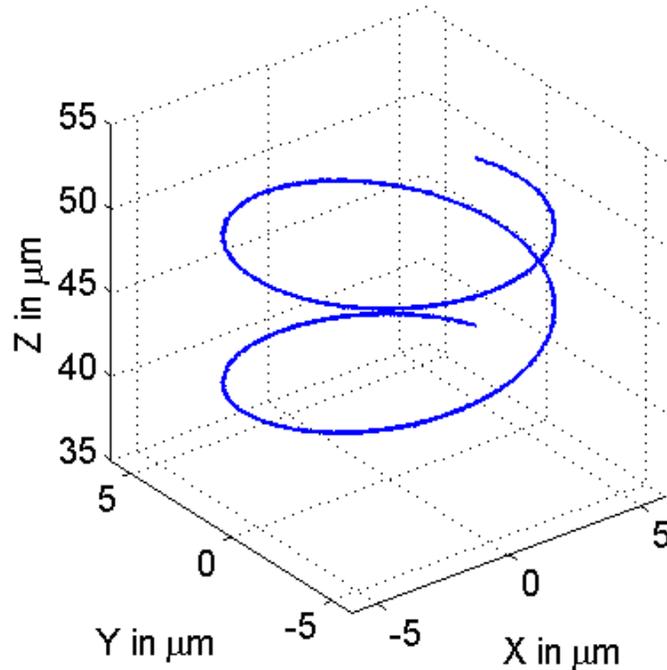


$r = 1 \mu\text{m}$; $v = 6.28 \mu\text{m/s}$
Circle in the x-y-plane

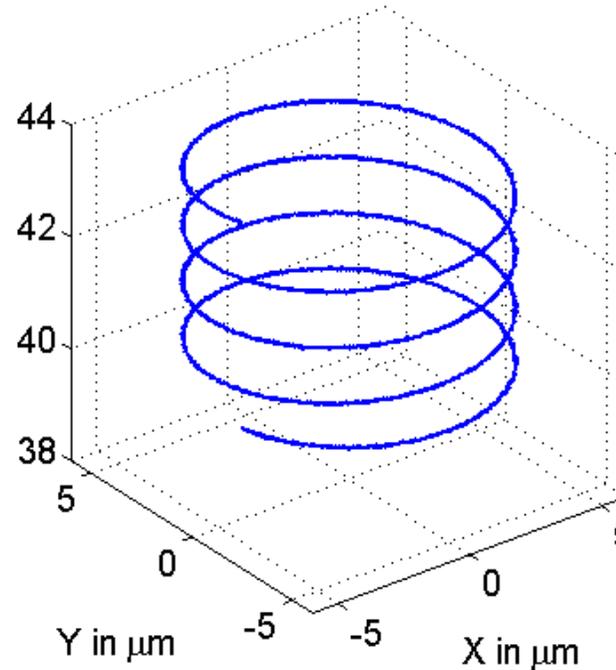


Mag6D - Platform ... Performance (4)

Helix: $d=10\mu\text{m}$, $f=1\text{Hz}$, $VelZ=10\mu\text{m/s}$



Helix: $d=10\mu\text{m}$, $f=1\text{Hz}$, $VelZ=1\mu\text{m/s}$



$v_z = 10 \mu\text{m/s}$

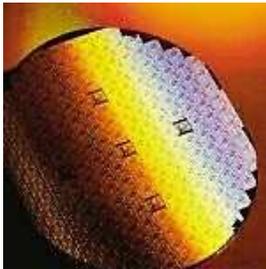
$v_z = 1 \mu\text{m/s}$

Helix movements with a diameter of $10 \mu\text{m}$ and different z -velocities

Mag6D - Platform ... for High-Tech Markets

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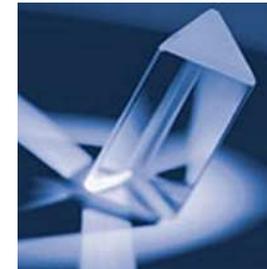
Semiconductor technology



Data storage technology



Microscopy



Metrology / laser systems



Life science / biotech



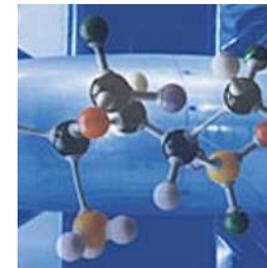
Photonics/ optics



Precision machining



Automation / handling



Nano-technology



Astronomy / aeronautics

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***Thank you for your
attention!***



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